

| | Type | Hits | Search Text | DBs | Time Stamp | Comments | Error Definition |
|----|------|------|--|----------|------------------|----------|------------------|
| 51 | IS&R | 1189 | (118/309,326).CCLS. | USPAT | 2002/08/20 15:11 | | |
| 52 | IS&R | 1692 | (427/240,585,99).CCLS. | USPAT | 2002/08/20 15:23 | | |
| 53 | IS&R | 1028 | (118/308).CCLS. | USPAT | 2003/02/04 14:02 | | |
| 54 | BRS | 3 | ((118/308).CCLS.) and dry near gas | USPAT | 2003/02/04 14:03 | | |
| 55 | BRS | 15 | ((118/308).CCLS.) and aerosol | USPAT | 2003/02/04 14:23 | | |
| 56 | IS&R | 799 | (118/319,320).CCLS. | USPAT | 2003/02/04 14:07 | | |
| 57 | IS&R | 868 | (118/52,612).CCLS. | USPAT | 2003/02/04 14:07 | | |
| 58 | BRS | 134 | wafer and aerosol same solid | USPAT | 2003/02/04 14:30 | | |
| 59 | BRS | 58 | (wafer and aerosol same solid) and deposit\$3 same solid | USPAT | 2003/02/04 14:31 | | |
| 60 | BRS | 13 | (wafer and aerosol same solid) and deposit\$3 same solid same wafer | USPAT | 2003/02/04 14:31 | | |
| 61 | BRS | 23 | deposition same aerosol same nozzle | US-RGPUB | 2003/02/05 09:25 | | |
| 62 | IS&R | 1 | ("5534309").PN. | USPAT | 2003/02/06 10:18 | | |
| 63 | BRS | 15 | "5534309" | USPAT | 2003/02/06 10:20 | | |
| 64 | BRS | 3 | "5534309" and impact\$3 | USPAT | 2003/02/06 15:05 | | |
| 65 | IS&R | 1 | ("5534309").PN. | USPAT | 2003/02/06 13:27 | | |
| 66 | BRS | 8 | "5534309" and aerosol | USPAT | 2003/02/06 15:05 | | |
| 67 | BRS | 0 | "5534309" and aerosol and bypass | USPAT | 2003/02/06 15:05 | | |
| 68 | BRS | 0 | bypass near deposition near chamber | USPAT | 2003/02/06 15:19 | | |

02/10/2003, EAST Version: 1.03.0007

similar case
04/7/26/88

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|----|------|------|---|-----------------|------------------|----------|------------------|
| 69 | BRS | 18 | bypass with deposition near chamber | USPAT | 2003/02/06 15:31 | | |
| 70 | BRS | 6124 | deposition near chamber | USPAT | 2003/02/06 15:32 | | |
| 71 | BRS | 7340 | deposition near chamber | USPAT; US-PGPUB | 2003/02/06 15:32 | | |
| 72 | BRS | 65 | (deposition near chamber) and (CNC or (particle near counter)) | USPAT; US-PGPUB | 2003/02/06 15:33 | | |
| 73 | BRS | 1 | 5746832.URPN. | USPAT | 2003/02/06 16:05 | | |
| 74 | BRS | 0 | pair same pressure same sensor\$1 same DMA | USPAT | 2003/02/07 15:05 | | |
| 75 | BRS | 4937 | pair same pressure same sensor\$1 | USPAT | 2003/02/07 15:06 | | |
| 76 | BRS | 172 | pair near pressure near sensor\$1 | USPAT | 2003/02/07 15:06 | | |
| 77 | BRS | 22 | (pair near pressure near sensor\$1) and (wafer or semiconductor) | USPAT | 2003/02/07 15:07 | | |
| 78 | BRS | 15 | (orifice\$1 or(flow near restrict\$3)) same DMA | USPAT | 2003/02/07 15:45 | | |
| 79 | BRS | 2 | (orifice\$1 or(flow near restrict\$3)) same DMA same vacuum | USPAT | 2003/02/07 15:20 | | |